

<b>Notice of References Cited</b>	Application/Control No. 10/676,819		Applicant(s)/Patent Under Reexamination WEDEL ET AL.	
	Examiner Qing Chen		Art Unit 2191	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,192,378 B1	02-2001	Abrams et al.	707/204
*	B	US-6,523,134 B2	02-2003	Korenshtein, Roni	714/16
*	C	US-7,155,666 B2	12-2006	Breuer et al.	715/255
*	D	US-7,174,481 B1	02-2007	Di Fabbrizio et al.	714/35
*	E	US-7,203,866 B2	04-2007	Di Fabbrizio et al.	714/38
*	F	US-7,249,174 B2	07-2007	Srinivasa et al.	709/223
*	G	US-7,299,450 B2	11-2007	Livshits et al.	717/121
*	H	US-2002/0138595 A1	09-2002	Ruellan et al.	709/219
*	I	US-2004/0006764 A1	01-2004	Van De Vanter et al.	717/112
*	J	US-2004/0205663 A1	10-2004	Mohamed, Ibrahim A.	715/530
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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	V	
	W	
	X	

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